

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2497	SERIAL NO. 10/776,553			
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Weimin Li et al.				
				FILING DATE February 10, 2004	GROUP 1755			
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date If Appropriate	
<i>DP</i> <i>6/22/05</i>	AA	5,994,217	11-1999	Ng	—	—		
	AB	5,991,217	11-1999	Tavrow et al.	—	—		
	AC	5,985,519	11-1999	Kakamu et al.	—	—		
	AD	5,747,388	05-1998	Kösters et al.	—	—		
	AE	5,639,687	06-1997	Roman et al.	—	—		
	AF	5,498,555	03-1998	Lin	—	—		
	AG	6,498,084B2	12-2002	Bergemont	—	—		
	AH	5,036,383	07-1991	Mori	—	—		
	AI	6,638,875	10-2003	Han et al.	—	—		
	AJ	6,720,247	04-2004	Kirkpatrick et al.	—	—		
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	AL	5,593,741	01-1997	Ikeda	—	—		
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclasses	Translation	
							Yes	No
<i>B</i>	AM	0 471185 A2	02/92	EPO	—	—		
<i>C</i>	AN	0 484515 A3	01/92	EPO	—	—		
<i>B</i>	AO	0 771888 A1	05/97	EPO	—	—		
<i>C</i>	AP	08-213388A	08-1996	Japan	—	—		
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
<i>C</i>	AR	Wolf, "Silicon Processing for the VLSI Era, Vol. 2: Process Integration," © 1990, pp. 189-190.						
<i>C</i>	AS	Wolf et al., "Silicon Processing for the VLSI Era - Vol. 1 - Process Technology," Prologue, page xodii (2 pages total).						
<i>C</i>	AT	Heavens, O.S., "Optical Properties of Thin Solid Films", pp. 48-49.						
EXAMINER <i>R</i>				DATE CONSIDERED <i>8/23/05</i>				
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>								

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